



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : Confirmation No. 1853  
Shoriki NARITA et al. : Docket No. 2001\_1876A  
Serial No. 10/019,700 : Group Art Unit 2825  
Filed January 2, 2002 : Examiner Igwe U. Anya

BUMP FORMING APPARATUS FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, CHARGE REMOVAL  
METHOD FOR CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE,  
CHARGE REMOVING UNIT FOR  
CHARGE APPEARANCE SEMICONDUCTOR  
SUBSTRATE, AND CHARGE APPEARANCE  
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED  
TO CHARGE ANY DEFICIENCY IN THE  
Fees FOR THIS PAPER TO DEPOSIT  
ACCOUNT NO. 23-0975

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**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Restriction Requirement of July 29, 2003, Applicants hereby elect Group I, which is drawn to an apparatus and is embodied by claims 1-13 and 25-39.

Having made the required election, a full examination on the merits of the elected group is requested.

Respectfully submitted,

Shoriki NARITA et al.

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August 29, 2003

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